

CHANG WAN HAN

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EDUCATION

- Aug. 2012 – Present **Purdue University**, West Lafayette, IN, USA
- **Ph. D. Student** in School of Materials Engineering (Advisor: Prof. Volkan Ortolan)
- Mar. 2007 – Feb. 2009 **Korea University**, Seoul, South Korea
- **M. E.** in Materials Science and Engineering (Advisor: Prof. Sang Ho Lim)
- Mar. 2002 – Feb. 2007 **Korea University**, Seoul, South Korea
- **B. E.** in Materials Science and Engineering (*Graduation with Honors*)

PUBLICATIONS

1. **C. W. Han**, J. K. Han, and S. H. Lim, *J. Magnetism*, 15, 116 (**2010**)
2. J. K. Han, **C. W. Han**, and S. H. Lim, *J. Korean Physical Society*, 55, 2505 (**2009**)
3. **C. W. Han** and S. H. Lim, *Jpn. J. Appl. Phys.*, 48, 123001 (**2009**)
4. **C. W. Han**, J. K. Han, and S. H. Lim, *J. Appl. Phys.*, 106, 094508 (**2009**)
5. **C. W. Han** and S. H. Lim, *J. Phys. D: Appl. Phys.*, 42, 045006 (**2009**)
6. D. H. Lee, **C. W. Han**, and S. H. Lim, *J. Korean Physical Society*, 54, 169 (**2009**)

PATENT

1. S. H. Lim and **C. W. Han**, Korea Patent No. 1010945570000 (**2011**)
2. S. H. Lim, **C. W. Han**, and J. K. Han, Korea Patent No. 1010832050000 (**2011**)

TECHNICAL SKILLS

- | | |
|--------------------------|--|
| • Characterization | Material properties
TEM (FEI Tecnai20, Titan80-300), SEM (JEOL JSM6400), XRD (Bruker D8, GADDS), VSM, 4 Point Probe, Surface profiler (KLA Tencor Alpha step)
Electrical properties
Probe-station, I-V (current-voltage), C-V (capacitance-voltage), Curve Tracer, Semiconductor parameter analyzer |
| • Micro/nano fabrication | Photolithography (Mask aligner, Spin coater, Hot plate, etc.), Thin film (Sputter, E-beam evaporator), Etch (Ion milling, Wet chemical etch, ICP etcher) |
| • Computer programs | MAUD (Rietveld refinement), MTEX (MATLAB toolbox for texture analysis), Micromagus (Micromagnetic simulation package), Origin, Autocad (2d design), CATIA (3d design), Labview (Core 1 level), Mathcad |